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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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TECHNOLOGY CENTER 2800

Applicants : Benedetto Vigna et al.  
Application No. : 09/658,294 ✓  
Filed : September 8, 2000  
For : METHOD FOR COMPENSATING THE POSITION OFFSET OF  
CAPACITIVE INERTIAL SENSOR, AND CAPACITIVE  
INERTIAL SENSOR

Examiner : Helen C. Kwok  
Art Unit : 2856  
Docket No. : 854063.582 ✓  
Date : October 18, 2002

Commissioner for Patents  
Washington, DC 20231

AMENDMENT

Commissioner for Patents:

In response to the Office Action mailed July 18, 2002, applicants respectfully request that the above-identified application be amended as follows:

In the Claims:

Please amend claims 1-3, 6-11, 13, 17-19, and 22-24 to read as follows:

1. (Amended) An inertial sensor made of semiconductor material, comprising a stator element and a rotor element electrostatically coupled together; and an actuator made of semiconductor material, coupled to said rotor element and controlled so as to compensate a position offset of the rotor element.